



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Nathan R. Brown

Serial No.: 10/715,264

Filed: November 17, 2003

For: METHODS FOR DETERMINING
AMOUNTS AND LOCATIONS OF
DIFFERENTIAL PRESSURE TO BE APPLIED
TO SEMICONDUCTOR SUBSTRATES
DURING POLISHING OF SEMICONDUCTOR
DEVICE STRUCTURES CARRIED THEREBY
AND FOR SUBSEQUENTLY POLISHING
SIMILAR SEMICONDUCTOR DEVICE
STRUCTURES

Confirmation No.: 5086

Examiner: S. Macarthur

Group Art Unit: 1763

Attorney Docket No.: 2269-4375.3US

(99-1029.03/US)

CERTIFICATE OF MAILING

I hereby certify that this correspondence along with any attachments referred to or identified as being attached or enclosed is being deposited with the United States Postal Service as First Class Mail on the date of deposit shown below with sufficient postage and in an envelope addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

December 6, 2006

Erika Gandre

Name (Type/Print)

Entered with RUE2141 mw2116A

RESPONSE TO FINAL OFFICE ACTION

Mail Stop AF Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Examiner:

This Response follows the final Office Action of October 6, 2006, the shortened statutory period for response to which expires on January 6, 2006. This Response is being submitted within two months of the mailing date of the final Office Action.